

PATENT APPLICATION

IN THE U.S. PATENT AND TRADEMARK OFFICE

June 23, 2004

Applicant(s): Kevin LANCON, et al

For: SYSTEM OF MONITORING OPERATING CONDITIONS OF ROTATING EQUIPMENT

Serial No.: 10/675 207 Group: 2859

Confirmation No.: 9935

Filed: September 30, 2003 Examiner: Unknown

Atty. Docket No.: Flowserve C-94

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

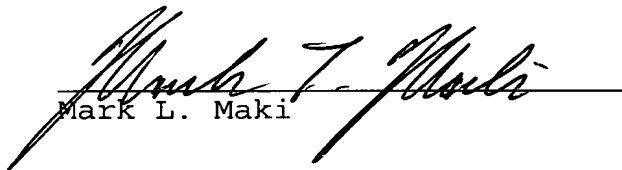
INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the provisions of Rules 1.97(b)(3) and 1.98, enclosed herewith is Form PTO-1449 (2 pages). Pursuant to 37 CFR 1.491(b) Applicants are not providing copies of the cited U.S. Patents, however, copies all publications listed thereon have been provided.

Further consideration is respectfully solicited.

Respectfully submitted,


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Reg. No. 24 323
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Reg. No. 36 589
Reg. No. 40 694
Reg. No. 36 328
Reg. No. 53 685
Reg. No. 24 949

Encl: Form PTO-1449 (2 pages)

110.0703

INFORMATION
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JUN 28 2004

U.S. PATENT DOCUMENTS

Examiner Initial*	Document Number	Date	Name	Class	Sub Class	Filing Date
AA	3 921 435	Nov 1975	Howard			
AB	4 691 276	Sep 1987	Miller, et al			
AC	4 781 064	Nov 1988	Yates			
AD	4 854 162	Aug 1989	Yerace, et al			
AE	5 041 989	Aug 1991	Kataoka, et al			
AF	5 050 092	Sep 1991	Perry			
AG	5 115 406	May 1992	Zatezalo, et al			
AH	5 381 692	Jan 1995	Winslow, et al			
AI	5 533 413	Jul 1996	Kobayashi, et al			
AJ	5 628 229	May 1997	Krone, et al			
AK	5 691 707	Nov 1997	Smith, et al			
AL	5 762 342	Jun 1998	Kakabaker, et al			
AM	5 992 237	Nov 1999	McCarty, et al			
AN	6 006 164	Dec 1999	McCarty, et al			
AO	6 065 345	May 2000	Holenstein, et al			

FOREIGN PATENT DOCUMENTS

Document Number	Date	Country	Class	Sub Class	Translation Yes No
AP					

OTHER DOCUMENTS (Including Author, Title, Date, Pages, Etc.)

AR	Rockwell International Corporation, ENTEK, "The Ten Most Common Reasons Why Oil Analysis Programs Fail and the Strategies That Effectively Overcome Them", Publication No. ENOAS-AT401A-EN-P, March 2001, pp. 1-12
AS	ENTEK IRD and Flowserve Flow Solutions Division, Condition Data Point Monitoring™, "Monthly Report - Complex 3/4 Machines", September 27, 2002, pp. 1-7

EXAMINER

DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

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Examiner Initial	Document Number	Date	Name	Class	Sub Class	Filing Date
	6 182 737	Jul 2000	Williamson, et al			
AB	6 161 962	Dec 2000	French, et al			
AC	6 202 491 B1	Mar 2001	McCarty, et al			
AD	6 208 953 B1	Mar 2001	Milek, et al			
AE	6 236 328 B1	May 2001	Smith, et al			
AF	6 241 383 B1	Jun 2001	Feller, et al			
AG	6 260 004 B1	Jul 2001	Hays, et al			
AH	6 271 761 B1	Aug 2001	Smith, et al			
AI	6 289 735 B1	Sep 2001	Dister, et al			
AJ	6 297 742 B1	Oct 2001	Canada, et al			
AK	6 330 525 B1	Dec 2001	Hays, et al			
AL	6 332 116 B1	Dec 2001	Qian, et al			
AM	6 360 616 B1	Mar 2002	Halliday, et al			
AN	6 425 293 B1	Jul 2002	Woodroffe, et al			

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	Document Number	Date	Country	Class	Sub Class	Translation Yes No
AP						

OTHER DOCUMENTS (Including Author, Title, Date, Pages, Etc.)

AR	ENTEK, Rockwell Automation, Integrated Condition Monitoring Solutions, "Enwatch™ Online Surveillance System" brochure, Publication No. ENOLS-TD302A-EN-P, March 2002
AS	ENTEK, Rockwell Automation, Integrated Condition Monitoring Solutions, "Enpac™ Family" brochure, Publication No. ENPOR-TD101B-EN-P, March 2002
AT	ENTEK, Rockwell Automation, "ENTEK XM™ - Machine Monitoring and Protection System" brochure, Publication No. ENMON-PP105A-EN-P, September 2002

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